



Docket No.: 060188-0658

**PATENT**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of	:	Customer Number: 20277
Masashi HAMANAKA, et al.	:	Confirmation Number: 8488
Application No.: 10/671,502	:	Group Art Unit: 3723
Filed: September 29, 2003	:	Examiner: RACHUBA, MAURINA T

For: POLISHING METHOD FOR SEMICONDUCTOR DEVICE, METHOD FOR  
FABRICATING SEMICONDUCTOR DEVICE AND POLISHING SYSTEM

**AMENDMENT**

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated July 15, 2005, having a three-month shortened statutory period for response set to expire October 15, 2005, a one-month extension up to and including November 15, 2005 being filed concurrently herewith, please amend the above-identified application as follows.